Amendment Dated: October 24, 2005

## Amendments to the Claims:

The listing of claims will replace all prior versions, and listings, of claims in the application:

## <u>Listing of Claims</u>:

1. (Currently Amended) A process system comprising:

a chamber;

a supply plate which has a plurality of gas holes and supplies a process gas into said chamber through said gas holes;

a first diffusion portion which diffuses said gas in a direction approximately horizontal parallel to a major surface of said supply plate; and

a second diffusion portion which leads said gas diffused by said first diffusion portion to said gas holes, said second diffusion portion comprised of a disk-like member having a groove formed in one side thereof, said groove having through holes formed therein, wherein said second diffusion portion is placed over said supply plate to form a hollow portion between said disk-like member and said supply plate such that said gas can be supplied from said first diffusion portion to said hollow portion; and

said process system further comprising a partition member in said hollow portion which separates said hollow portion into a center area and an end area, and a gas supply portion comprising mutually independent gas flow passages, wherein at least one gas flow passage supplies said gas via through holes to said center area, and at least one gas flow passage supplied said gas via through

holes to said end area, wherein the gas flow rates in the mutually independent gas flow passages are independently controlled.

- 2. (Original) The process system according to claim 1, wherein said first diffusion portion is comprised of a disk like member having a plurality of grooves formed in one side thereof and communicating with one another and through holes formed in said plurality of grooves and led to the other side.
- 3. (Currently Amended) The process system according to claim 2, wherein at least one of said grooves in said first diffusion portion are provided at positions to which said gas is supplied, and said gas supplied to said at least one groove is dispersed to the other grooves in said first diffusion portion and flows out to the other side through said through holes respectively provided in said other grooves.
  - 4. (Canceled).
- 5. (Currently Amended) The process system according to claim [[4]] 2, wherein said disk-like member constituting said second diffusion portion is made of a same member as said disk-like member constituting said fast first diffusion portion, and said groove constituting said second diffusion portion and said grooves constituting said first diffusion portion are formed in opposite sides of said member.

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6. (Canceled).

7. (Original) The process system according to claim 1, wherein said

first diffusion portion is comprised of a cylindrical member having a plurality of

linear holes communicating with one another, formed by boring and sealing end

portions of bored portions, at least one of said holes is supplied with said gas and

said gas supplied to said at least one hole is dispersed to the other holes.

8. (Currently Amended) The process system according to claim 7,

wherein said cylindrical member has connection holes provided in such a way as

to be led to in communication with said other linear holes from its one side, and

said gas supplied to said other linear holes is supplied to said second diffusion

portion from said connection holes.

9. (Withdrawn)

10. (Currently Amended) The process system according to claim 1,

wherein a linear gas flow passage approximately horizontal parallel to a major

surface of said supply plate is formed in said first diffusion portion, and said gas

is diffused in a direction approximately horizontal parallel to the major surface

of said supply plate linearly.

11. (Currently Amended) The process system according to claim 7,

wherein said first diffusion portion has a plurality of cylindrical members, and

each cylindrical member comprises said plurality of liner linear holes which are provided at different positions in a direction of thickness of said cylindrical member formed from a sidewall of said cylindrical members toward a center thereof.

12. (Currently Amended) The process system according to claim 11, wherein said plurality of linear holes cylindrical members respectively constitute gas flow passages independent from each other.

## 13-19. (Withdrawn)

- 20. (New) The process system according to claim 1, wherein each mutually independent gas flow passage is adapted to receive said process gas from a common gas supply source.
  - 21. (New) A process system comprising:
  - a chamber;
- a supply plate which has a plurality of gas holes and supplies a process gas into said chamber through said gas holes;
- a first diffusion portion which diffuses said gas in a direction approximately parallel to a major surface of said supply plate; and
- a second diffusion portion which leads said gas diffused by said first diffusion portion to said gas holes,

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wherein said first diffusion portion and said second diffusion portion comprise mutually independent gas flow passages, wherein at least one gas flow passage supplies said process gas into a center area of said chamber, and at least one gas flow passage supplies said process gas into an end area of said chamber, wherein the process gas in a first independent gas flow passage and the process gas in a second independent gas flow passage do not mix before flowing into said chamber.

22. (New) The process system according to claim 21, wherein the process gas flow rates in the mutually independent gas flow passages are independently controlled.